

ABSTRACT OF THE DISCLOSURE

ILLUMINANCE METER, ILLUMINANCE MEASURING METHOD USING THEREWITH
AND EXPOSURE APPARATUS

According to the present illuminance meter 8, the present method of measuring illuminance, and an exposure apparatus based on the method, because the instrument plate 9 of the illuminance meter is the same size as the substrate W to be exposed, the illuminance meter can be handled in a manner similar to the substrate by installing a substrate exchanger or robotic exchanger 11, 44 on the substrate stage WST, and there is no need for the operator to manually position the illuminance meter on the substrate stage, and further, the illuminance meter as a probe can easily be positioned on the substrate stage with high precision.

This Sheet Has Been Replaced

